



Sheet 1 of 1

Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No. 30848/40323	Serial No. 10/502,465
INFORMATION DISCLOSURE STATEMENT		Applicant Androula G. Nassiopoulou	
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U.S. PATENT DOCUMENTS							
*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate	
<i>FAR</i>	6,359,276 B1	03/19/02	Tu	250	338.1	07/06/99	

FOREIGN PATENT DOCUMENTS							
*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No
<i>FAR</i>	1,251,945	05/03/00	China			Abstract only	
<i>FAR</i>	WO 98/50763	11/12/98	PCT				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	
<i>FAR</i>	"Porous Silicon Bulk Micromachining for Thermally Isolated Membrane Formation", Dücsö et al., Sensors and Actuators, A 60, 1997, pp. 235-239
<i>FAR</i>	"Micromachined Silicon Thermopile and Thermal Radiators Using Porous Silicon Technology", Dobrzański et al., IEE Proc.-Optoelectron, Vol. 145, No. 5, October 1998, pp. 307-311
<i>FAR</i>	"Frontside Bulk Silicon Micromachining Using Porous-Silicon Technology", Kaltsas et al., Sensors and Actuators A 65, 1998, pp. 175-179
<i>FAR</i>	"Novel C-MOS Compatible Monolithic Silicon Gas Flow Sensor with Porous Silicon Thermal Isolation", Kaltsas et al., Sensors and Actuators 76, 1999, pp. 133-138
<i>FAR</i>	"Permeated Porous Silicon for Hydrocarbon Sensor Fabrication", Angelucci et al., Sensors and Actuators 74, 1999, pp. 95-99
<i>FAR</i>	"Free-Standing, Mobile 3D Porous Silicon Microstructures", Lammel et al., Sensors and Actuators 85, 2000, pp. 356-360
<i>FAR</i>	"Porous Silicon as an Effective Material for Thermal Isolation on Bulk Crystalline Silicon", Nassiopoulou et al., Phys. Stat. Sol. (a) 182, 2000, pp. 307-311
<i>FAR</i>	"Multi-Walled Microchannels: Free-Standing Porous Silicon Membranes for Use in μ TAS", Tjerkstra et al., Journal of Microelectromechanical Systems, Vol. 9, No. 4, December 2000, pp. 495-501
<i>FAR</i>	International Search Report in PCT/GR03/00003 dated April 23, 2003

Examiner <i>Rudolf F. Rosenberger, E</i>	Date Considered <i>5/3/2005</i>
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